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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/827,556	04/19/2004	Chan Hwang	8028-43 (SPX200304-0016US	3434
22150 F. CHAU & A	7590 04/05/2007 SSOCIATES, LLC		EXAM	INER
130 WOODBU	JRY ROAD		ROSASCO, STEPHEN D	
WOODBURY	, NY 11/9/		ART UNIT	PAPER NUMBER
			1756	
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SHORTENED STATUTO	RY PERIOD OF RESPONSE	MAIL DATE	DELIVERY MODE	
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Please find below and/or attached an Office communication concerning this application or proceeding.

If NO period for reply is specified above, the maximum statutory period will apply and will expire 6 MONTHS from the mailing date of this communication.

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<u>-</u>		Application No.	Applicant(s)	
	OSS A 4	10/827,556	HWANG ET AL.	
	Office Action Summary	Examiner	Art Unit	
		Stephen Rosasco	1756	
 Period for	The MAILING DATE of this communication Reply	appears on the cover sheet wi	th the correspondence address	
A SHO WHICH - Extensi after SI - If NO p - Failure Any rep	RTENED STATUTORY PERIOD FOR RE HEVER IS LONGER, FROM THE MAILING ions of time may be available under the provisions of 37 CFI X (6) MONTHS from the mailing date of this communication eriod for reply is specified above, the maximum statutory pe to reply within the set or extended period for reply will, by st oly received by the Office later than three months after the m patent term adjustment. See 37 CFR 1.704(b).	OF THIS COMMUNIC R 1.136(a). In no event, however, may a re ricod will apply and will expire SIX (6) MON tatute, cause the application to become AB	CATION. eply be timely filed THS from the mailing date of this communic ANDONED (35 U.S.C. & 133)	
Status				
2a)□ T 3)□ S	Responsive to communication(s) filed on <u>1</u> This action is FINAL . 2b) Since this application is in condition for allowed in accordance with the practice und	This action is non-final. wance except for formal matte	-	s is
	n of Claims			
44 5)	ne specification is objected to by the Examine drawing(s) filed on 19 April 2004 is/are: pplicant may not request that any objection to	drawn from consideration. ad/or election requirement. aniner. ani⊠ accepted or bn objecthe drawing(s) be held in abeyan	ce. See 37 CFR 1.85(a).	
	eplacement drawing sheet(s) including the cor ne oath or declaration is objected to by the			
Priority un	der 35 U.S.C. § 119			•
12)⊠ Ao a)⊠ 1 2 3	cknowledgment is made of a claim for fore All b) Some * c) None of: Certified copies of the priority docum Certified copies of the priority docum Copies of the certified copies of the papplication from the International Bure the attached detailed Office action for a	ents have been received. ents have been received in Appriority documents have been reau (PCT Rule 17.2(a)).	oplication No received in this National Stage	
Attachment(s	•			
2) Notice o	of References Cited (PTO-892) of Draftsperson's Patent Drawing Review (PTO-948) tion Disclosure Statement(s) (PTO/SB/08) lo(s)/Mail Date	Paper No(s)	ummary (PTO-413) //Mail Date formal Patent Application 	

Application/Control Number: 10/827,556

Art Unit: 1756

Detailed Action

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- (e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

Claims 1, 9 and 14 are rejected under 35 U.S.C. 102(b) as being anticipated by Pierrat (5,935,734).

Pierrat teaches a method of fabricating a photomask comprising patterning a first layer of photoresist over a layer of opaque material on a photomask substrate, and then etching the layer of opaque material through the openings in the first layer of photoresist to create corresponding openings in the layer of opaque material.

Claims 1, 9 and 14 are rejected under 35 U.S.C. 102(e) as being anticipated by Kim (7,022,438).

Kim teach a photomask comprising: a transparent substrate; a plurality of line-type opaque patterns formed on the transparent substrate, for defining floodlighting portions for forming patterns; and phase-shifting regions arranged on the transparent substrate between the opaque patterns at predetermined intervals, the phase-shifting regions defining floodlighting portions for contact holes.

And wherein the opaque pattern is an opaque layer.

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The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 1-18 are rejected under 35 U.S.C. 103(a) as being unpatentable over Pierrat (5,935,734) or Kim (7,022,438) in view of Kawata et al. (6,830,852).

The claimed invention is directed to a photomask comprising a plurality of light-shielding patterns aligned over a transparent substrate in two dimensions, each of the light-shielding patterns having length and width measurements that differ from each other; and at least one through hole penetrating a predetermined region of each of the light-shielding patterns to expose the transparent substrate.

And wherein the plurality of light-shielding patterns, aligned in two dimensions, have equal length and width measurements.

And wherein longitudinal axes of the light-shielding patterns having equal length and width measurements are in parallel.

The teachings of Pierrat or Kim differ from those of the applicant in that the applicant teaches the plurality of light-shielding patterns, aligned in two dimensions, have equal length and width measurements, and are in parallel.

Kawata et al. teach a stencil reticle, comprising a reticle membrane defining apertures having respective opening profiles corresponding to respective pattern elements defined by the reticle, wherein, among the pattern elements defined by the reticle, (a) a linearly extended pattern element having a width less than a predetermined division criterion (L) and a length equal to or greater than L is

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complementarily divided into respective linear pattern-element portions each having a respective length less than L, and (b) a large-area pattern element having both length and width equal to or greater than L is complementarily divided into respective linear pattern-element portions each having a respective width less than L and a respective length equal to or greater than L.

It would have been obvious to one having ordinary skill in the art to take the teachings of Pierrat or Kim and combine them with the teachings of Kawata et al. in order to make the claimed invention because as Kawata et al. teach, in this way the pattern elements are divided so as to reduce size errors that otherwise would be excessive at corners of the pattern elements when projected onto a substrate. i.e., whenever the size error exceeds a predetermined tolerance, then the pattern element is complementarily divided.

Conclusion

Any inquiry concerning this communication or earlier communications from the Examiner should be directed to Stephen Rosasco whose telephone number is (571) 272-1389. The Examiner can normally be reached Monday-Friday, from 8:00 AM to 4:30 PM. The Examiner's supervisor, Mark Huff, can be reached on (571) 272-1385. The fax phone number for the organization where this application or proceeding is assigned is (571) 273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

S. Rosasco

Primary Examiner

Jasco

Art Unit 1756

S.Rosasco 03/29/07